



"RESPONSE UNDER 37 CFR 1.116-
EXPEDITED PROCEDURE EXAMINING
GROUP 2813"

Docket No.: 207224US0

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

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RE: Application Serial No.: 09/846,255

Applicants: Satoshi KIKUCHI, et al.

Filing Date: May 2, 2001

For: CLEANING PROCESS FOR SUBSTRATE SURFACE

Group Art Unit: 2813

Examiner: L. Schillinger

SIR:

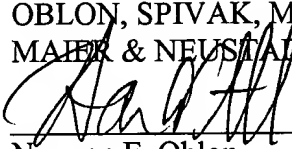
Attached hereto for filing are the following papers:

REQUEST FOR RECONSIDERATION AFTER FINAL

Our check in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
SATOSHI KIKUCHI ET AL : EXAMINER: SCHILLINGER, L.
SERIAL NO: 09/846,255 :
FILED: MAY 2, 2001 : GROUP ART UNIT: 2813
FOR: CLEANING PROCESS FOR
SUBSTRATE SURFACE

REQUEST FOR RECONSIDERATION AFTER FINAL

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Responsive to the Final Office Action dated July 17, 2002, Applicants respectfully request reconsideration of the above-identified application in view of the following remarks.

Claims 1-13 remain pending in the application.

REMARKS

The rejection of Claims 1-13 under 35 U.S.C. §103(a) as unpatentable over U.S. 5,635,102 (Mehta) in view of U.S. 5,922,624 (Verhaverbeke et al), is respectfully traversed.

As recited in Claim 1, the present invention is a process for cleaning a surface of a substrate, said surface carrying thereon a high-density film and a low-density film lower in density than said high-density film in combination, which comprises continuously bringing a mixed gas of anhydrous hydrogen fluoride gas and a heated inert gas into contact with said